

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: **Daisuke KOMADA, et al.**

Serial No.: **Not Yet Assigned**

Filed: **January 30, 2002**

For: **METHOD OF MANUFACTURING SEMICONDUCTOR DEVICE HAVING
SILICON CARBIDE FILM**



INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
Washington, D.C. 20231

January 30, 2002

Sir:

In compliance with 37 CFR 1.56, Applicants call to the attention of the Patent and Trademark Office the reference listed on the attached PTO-1449.

A copy of the reference is enclosed herewith.

In the event there are any fees due in connection with the filing of this paper, please charge

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Respectfully submitted,
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A handwritten signature of Ken-Ichi Hattori.

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Enclosures: PTO-1449; Reference (1)